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Results of Search in US Patent Collection db for:**(AN/"Cavendish Kinetics" AND AC/"San Jose"):** 48 patents.

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AN/"Cavendish Kinetics" AND AC/"San Jose"

PAT. NO.	Title
1 11,114,265	Thermal management in high power RF MEMS switches
2 10,964,505	Naturally closed MEMs switch for ESD protection
3 10,896,787	Contact in RF-switch
4 10,749,247	Multi-resonant antenna structure
5 10,707,039	Current handling in legs and anchors of RF-switch
6 10,594,024	Head-hand capacitance compensation with digital variable capacitor
7 10,566,163	MEMS RF-switch with controlled contact landing
8 10,566,140	DVC utilizing MEMS resistive switches and MIM capacitors
9 10,446,929	Antenna efficiency enhancement by active detuning of diversity antenna
10 10,418,717	Method and apparatus of maintaining constant antenna resonant frequency and impedance match in the presence of environmental changes and head/hand effect using variable reactance antenna aperture tuners
11 10,403,442	Method of manufacturing a MEMS DVC device
12 10,301,173	RF MEMS electrodes with limited grain growth
13 10,224,614	Head-hand capacitance compensation with digital variable capacitor
14 10,224,164	Merged legs and semi-flexible anchoring having cantilevers for MEMS device
15 10,163,566	DVC utilizing MIMS in the anchor
16 10,038,415	Power amplifier matching circuit with DVCs
17 10,029,914	Internally generated DFT stepped hysteresis sweep for electrostatic MEMS
18 10,029,909	Non-symmetric arrays of MEMS digital variable capacitor with uniform operating characteristics
19 9,948,212	Method and technique to control MEMS DVC control waveform for lifetime enhancement
20 9,908,774	Method for achieving good adhesion between dielectric and organic material
21 9,812,780	Techniques of tuning an antenna by weak coupling of a variable impedance component
22 9,754,724	Stress control during processing of a MEMS digital variable capacitor (DVC)
23 9,711,291	MEMS digital variable capacitor design with high linearity
24 9,711,290	Curved RF electrode for improved Cmax
25 9,711,289	Control-electrode shielding for improved linearity of a MEMS DVC device
26 9,708,177	MEMS device anchoring
27 9,589,731	MEMS variable capacitor with enhanced RF performance

- 28 [9,487,395](#)  [Method of forming planar sacrificial material in a MEMS device](#)
- 29 [9,443,658](#)  [Variable capacitor compromising MEMS devices for radio frequency applications](#)
- 30 [9,385,594](#)  [Two-state charge-pump control-loop for MEMS DVC control](#)
- 31 [9,373,447](#)  [Routing of MEMS variable capacitors for RF applications](#)
- 32 [9,336,953](#)  [MEMS lifetime enhancement](#)
- 33 [9,171,966](#)  [Implantation of gaseous chemicals into cavities formed in intermediate dielectrics layers for subsequent thermal diffusion release](#)
- 34 [9,076,808](#)  [RF MEMS isolation, series and shunt DVC, and small MEMS](#)
- 35 [9,019,756](#)  [Architecture for device having cantilever electrode](#)
- 36 [9,018,717](#)  [Pull up electrode and waffle type microstructure](#)
- 37 [8,957,485](#)  [Fabrication of MEMS based cantilever switches by employing a split layer cantilever deposition scheme](#)
- 38 [8,921,953](#)  [Method for MEMS device fabrication and device formed](#)
- 39 [8,921,165](#)  [Elimination of silicon residues from MEMS cavity floor](#)
- 40 [8,861,218](#)  [Device containing plurality of smaller MEMS devices in place of a larger MEMS device](#)
- 41 [8,786,933](#)  [Fabrication of a floating rocker MEMS device for light modulation](#)
- 42 [8,736,404](#)  [Micromechanical digital capacitor with improved RF hot switching performance and reliability](#)
- 43 [8,513,043](#)  [Method for MEMS device fabrication and device formed](#)
- 44 [8,488,230](#)  [Fabrication of a floating rocker MEMS device for light modulation](#)
- 45 [8,203,880](#)  [Binary logic utilizing MEMS devices](#)
- 46 [8,124,527](#)  [CMP process flow for MEMS](#)
- 47 [7,965,547](#)  [Arrangement and method for controlling a micromechanical element](#)
- 48 [7,867,886](#)  [Method of enclosing a micro-electromechanical element](#)
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